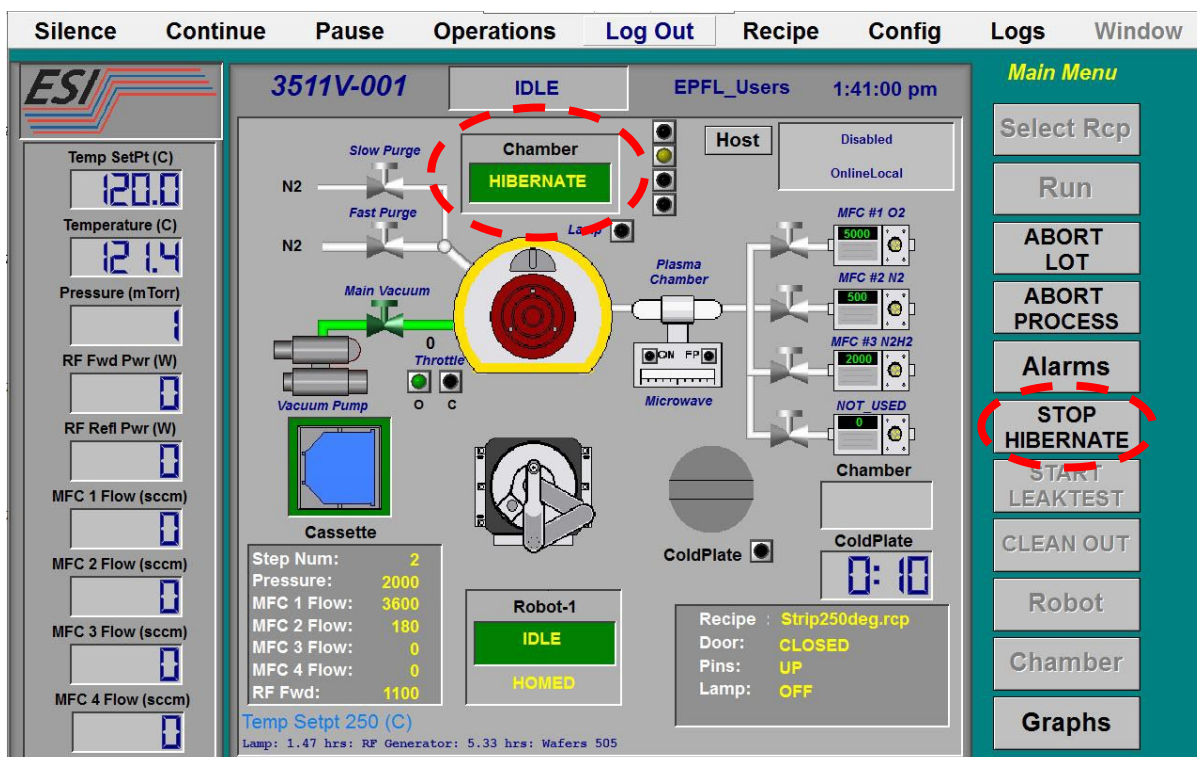# ESI 3511 Downstream Plasma Asher

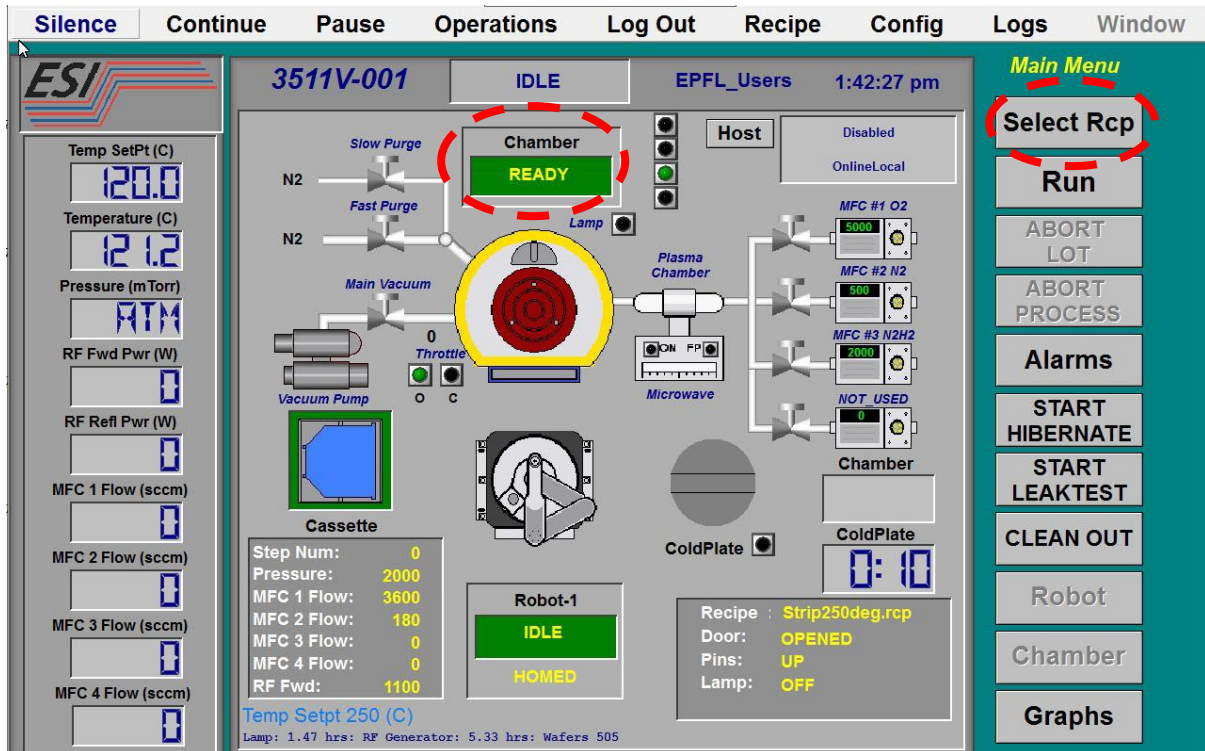The control interface might be logged out (most menus are grey-unavailable). If so, click on "**Log In**" top of screen and select "**EPFL_Users**". Password is "**1**".
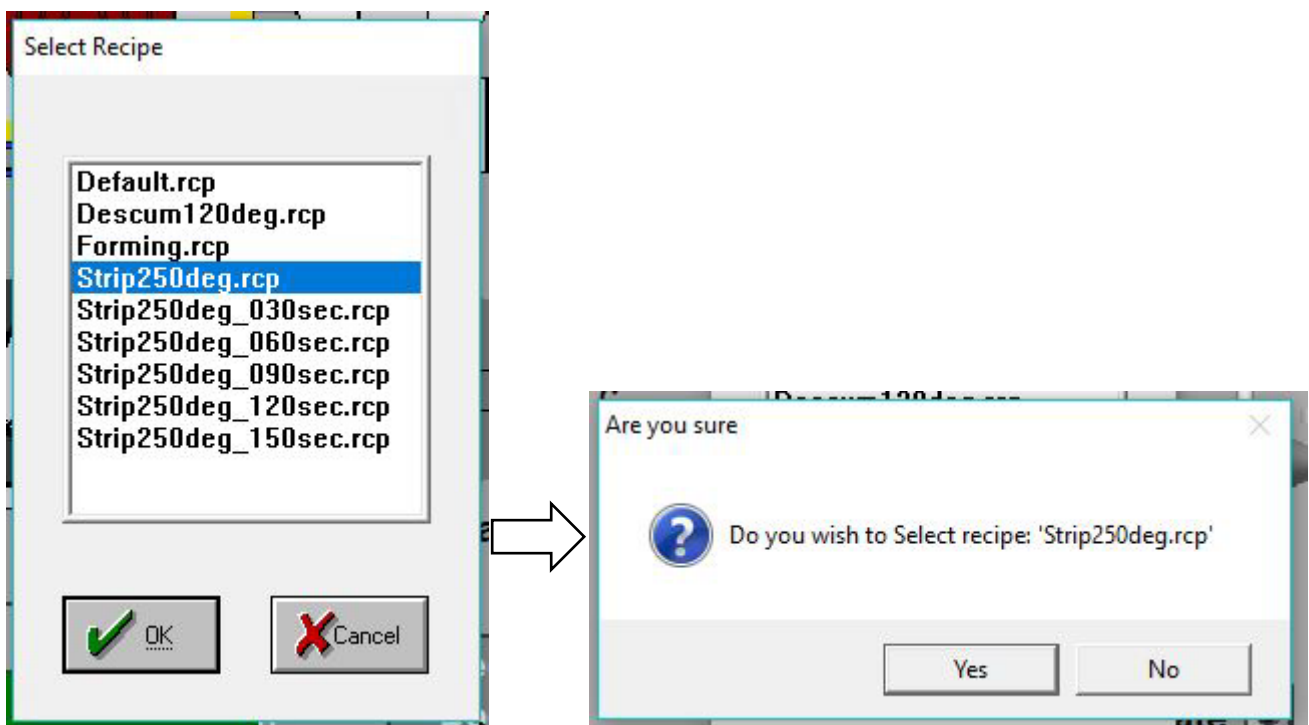

Chamber might be at "HIBERNATE" state. If so, no recipe can be started.
Click on "**Stop Hibernate**" and wait for the chamber to return at atmospheric pressure.

The chamber is now "READY" and the button "**Select Rcp**" is available.

Click on "**Select Rcp**", make you selection according to your needs, and confirm "**Yes**".

The chamber now reads "SET_UP". It is stabilizing the temperature to reach recipe setpoint.
When the chamber is OK for process it reads "READY".

Load your wafers in the cassette. **Please mind the position of your wafers**:
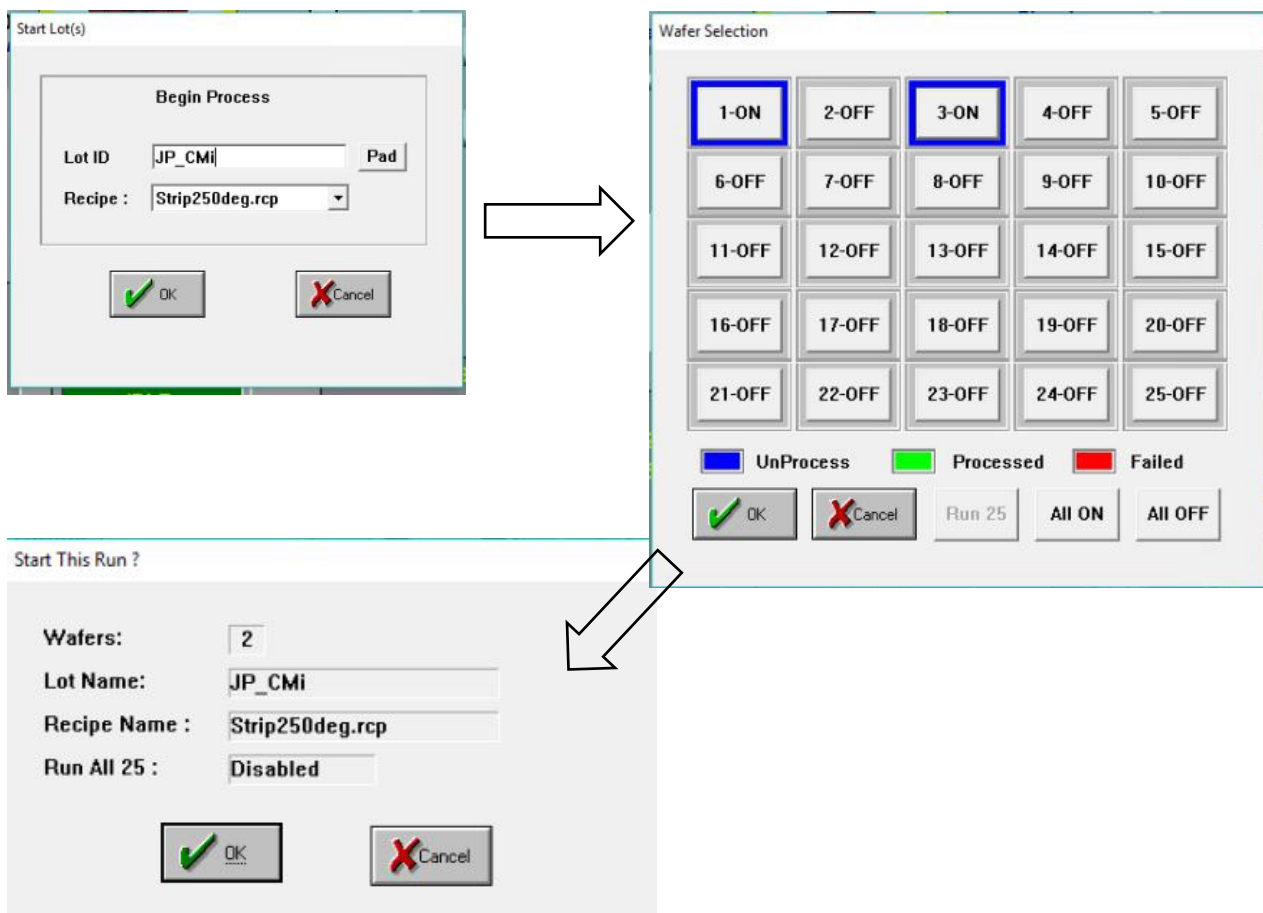
- Make sure the wafers are loaded horizontal!!
- Remember about slots number your wafers are loaded into.
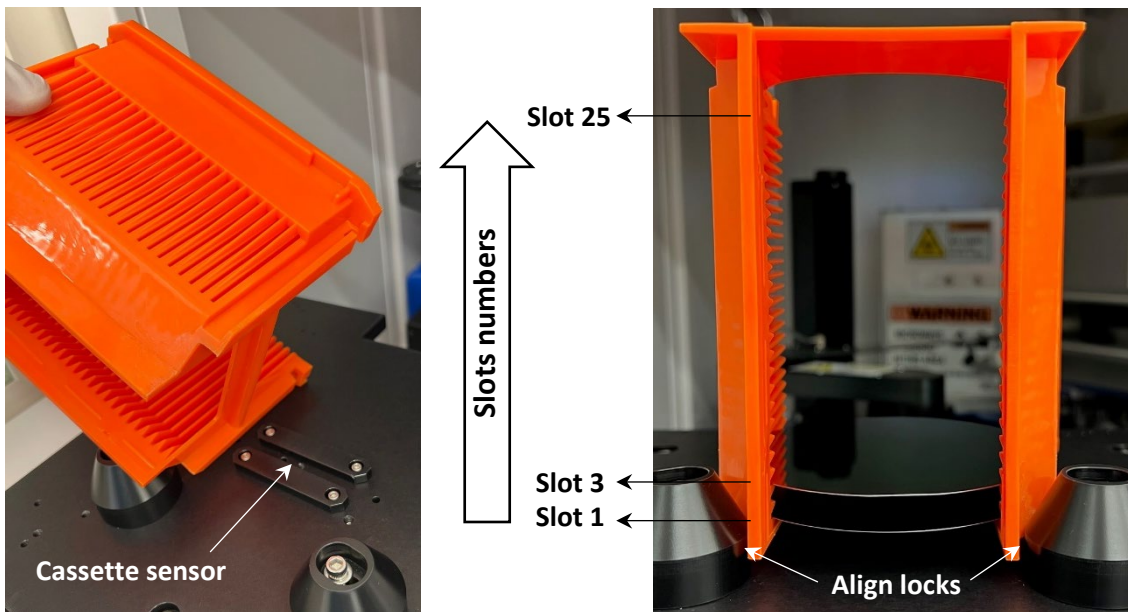
Click "**Run**" button, input your **lot ID** (optional), and click **OK**.
Select the wafers "**ON**" according to where the wafers are physically loaded in the cassette and confirm **OK**.
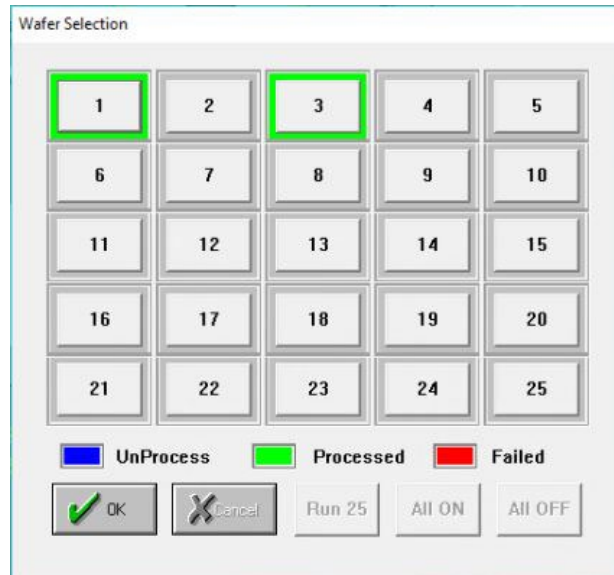Confirm "**OK**" to start the run.

The "**Robot-1**" Status will change from "IDLE" to "TRANSFER".

Through the process, live value of each parameters can be visualized by using the button "**Graphs**". This include optical end-point detection.

At end of the process, the summary of processed wafers appears.

Collect the wafers, place the cassette back to correct position, and "**Start Hibernate**" the chamber.